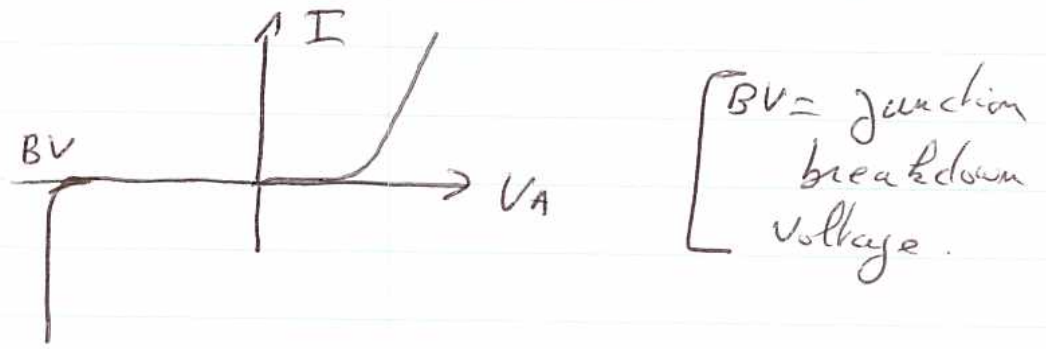


### "Impact ionization"

When an  $e^-$  is accelerated to high  $E$ , its kinetic energy can be equal or larger than the bandgap  $E_g$ . That energy can be released through a collision event while creating  $e^-$ -hole pair. So instead of having 1  $e^-$  at high energy we have 2 free  $e^-$  + 1 hole. We call it generation "by impact ionization".  
 $\Rightarrow$  avalanche multiplication phenomenon.

In the P-N junction a sudden increase of current is observed  $\Rightarrow$  breakdown.



### Remark:

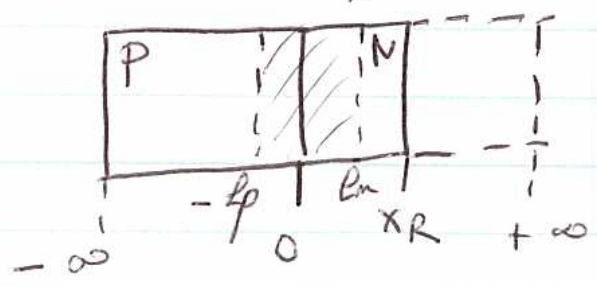
If N-type and P-type regions are heavily doped, the width of the depletion region is very small, and  $e^-$  can directly tunnel from P-type valence into N-type conduction band. These diodes are called "Zener diodes" where can be accurately controlled while adjusting concentration. Zener diodes are then used as voltage reference.

### ② Shut-base diode

previously we assume that the length of the P and N quasi-neutral region  $\gg$  diffusion length of the minority carriers

The term 'shut base' comes from bipolar transistors that consist in two P-N junctions PNP or NPN and the central region is called 'base'.

Consider a P-type region  $\gg L_n$   
a N-type region 'shut base' compared to  $L_p$ .



The previous assumption  $p_n(x \rightarrow \infty) = p_{n0}$  must be replaced by  $p_n(x_R) = p_{n0}$ .

In addition the minority holes will not be able to recombine in the base  $\Rightarrow J_p = \text{cte. (constant)}$

$$J_p = -q D_p \frac{dp}{dx} \Rightarrow p(x) = -\frac{J_p x}{q D_p} + B \quad (\text{linear function})$$

at  $x = L_n$   $p(x = L_n) = p_{n0} \exp(q V_A / \beta)$

$$\Rightarrow B = p_{n0} \exp(q V_A / \beta) + \frac{J_p L_n}{q D_p}$$

\*  $A B_0$

$$P(x_R) = P_{no} = -\frac{J_{pR}}{qD_p} + P_{no} \exp\left(\frac{qVA_{\beta}}{\beta}\right) + \frac{J_{pL}}{qD_p}$$

$$\Rightarrow J_p = \frac{qD_p P_{no}}{x_R - L_m} \left[ \exp\left(\frac{qVA_{\beta}}{\beta}\right) - 1 \right]$$

### ④ PN junction Capacitance

So far we considered only steady state characteristics. In practical application, it is important to know how quickly the device can adjust to a new bias condition (transient effects).

Capacitance calculation will help to estimate this 'time response' of the device.

Capacitance is measure of charge stored per unit change of voltage  $\Rightarrow$  if capacitance is large, this means more charge must be moved in or out, so that for a fixed current  $\Rightarrow$  more time is needed to complete the process.

In P-N junction two major capacitance =

- (i) capacitance associated with the charge which must be moved in or out of the depletion region.  $\Rightarrow$  depletion capacitance.
- (ii) " diffusion capacitance " under forward bias due to minority carriers.

(1) depletion capacitance

we know that

$$l_p = \sqrt{\frac{2\epsilon (V_0 - V_A) N_d}{q N_A (N_A + N_d)}}$$

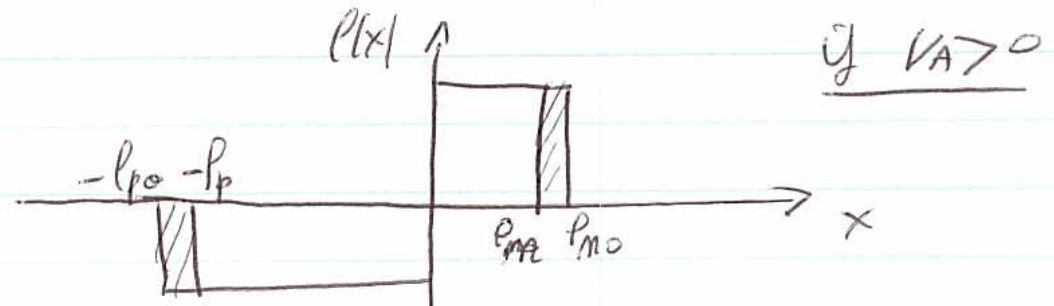
$$l_n = \sqrt{\frac{2\epsilon (V_0 - V_A) N_A}{q N_d (N_A + N_d)}}$$

The charge of the fixed, ionized doping impurities in each depletion region is (absolute value)

$$Q = A q N_d l_n = A q N_A l_p$$

in Coulombs.

[ A = cross-section of the junction ]



Capacitance is  $C_T = \left| \frac{dQ}{dV_A} \right| = A q N_d \left| \frac{dl_n}{dV_A} \right|$

$$\Rightarrow \boxed{C_T = A \frac{\epsilon}{l_n + l_p}} = \left[ \begin{array}{l} \text{Capacitance of} \\ \text{parallel plate capacitor} \\ \text{with a dielectric of permittivity} \\ \epsilon \end{array} \right]$$

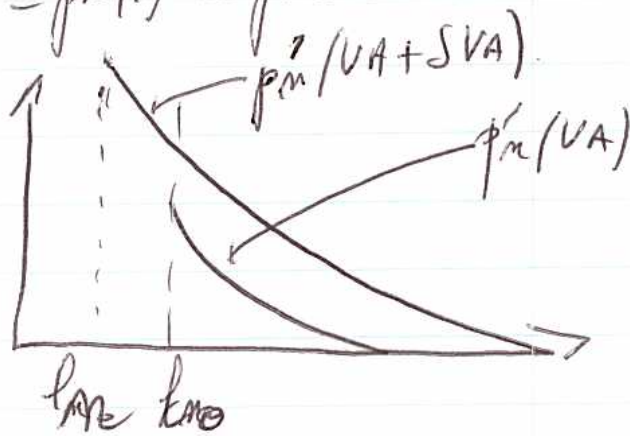
(ii) Diffusion capacitance

hole concentration in the p-type region

$$p_n(x) = p_{n0} + p_{n0} [\exp(qV_A/kT) - 1] \exp(-x/L_p)$$

excess concentration

$$p_n'(x) = p_n(x) - p_{n0}$$



$$Q = q \int_{x=0}^{\infty} p_n'(x) dx = q p_{n0} [\exp(qV_A/kT) - 1] \times L_p$$

$$\boxed{C_{Dp} = \frac{dQ}{dV_A} = \beta q^2 L_p p_{n0} \exp(qV_A/kT)}$$

AB.  $\boxed{C_{Dp} = \beta q \tau_p J_p / (kT)}$

Similarly  $C_{Dn} = \beta q \tau_n J_n / (-kT)$

$$\Rightarrow \boxed{C_D = C_{Dp} + C_{Dn} = \beta q [\tau_p J_p / (kT) + \tau_n J_n / (-kT)]}$$

# II Metal-semiconductor contacts

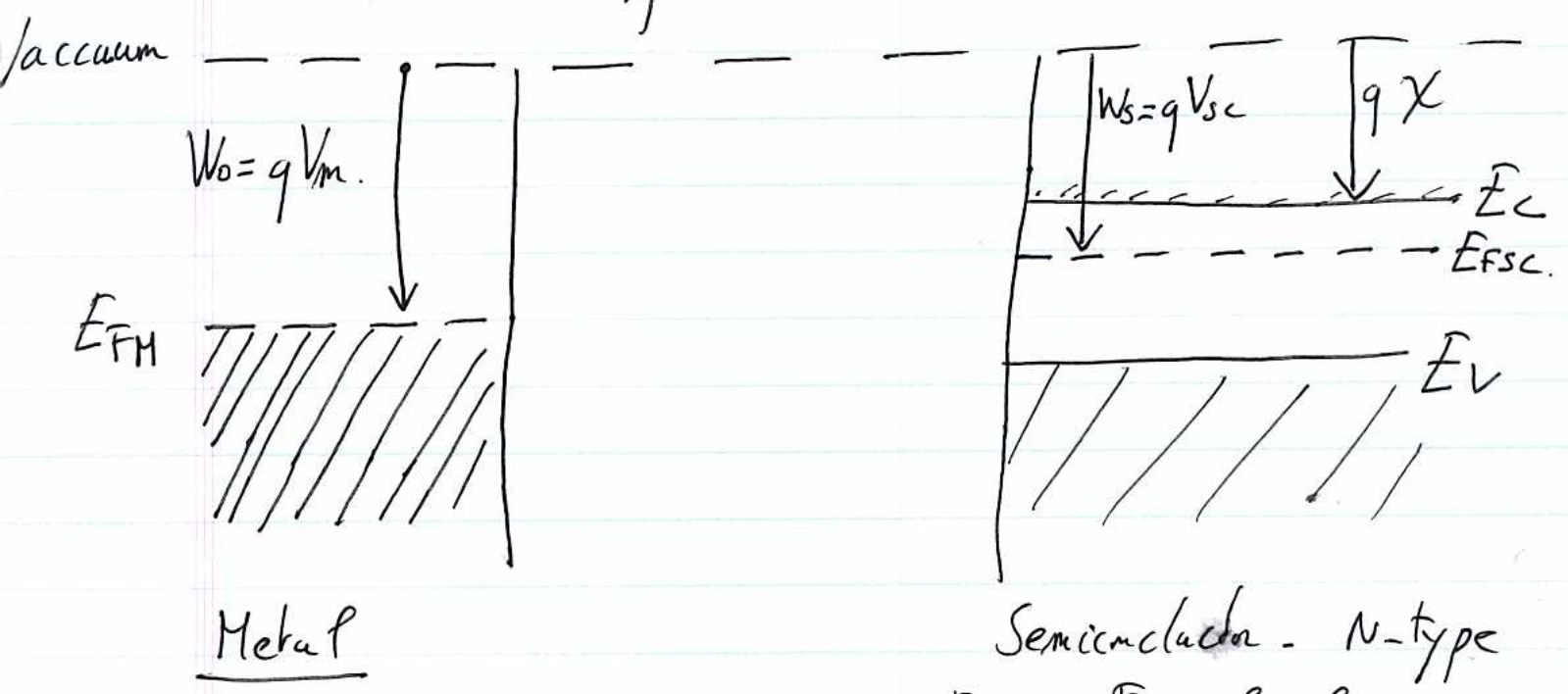
2 different types of metal-semiconductor contacts:

- (i) a Schottky contact = non-linear, rectifying current voltage characteristics:
- (ii) an Ohmic contact = linear, non-rectifying

## (I) Schottky diode

### (a) Unbiased junction

Consider a N-type semiconductor and a metal.



$E_{FM}$  = Fermi-level of the metal.  
 $W_0$  = work function energy required to extract an  $e^-$  at  $E_{FM}$

$E_{FSC}$  = Fermi level  
 $W_s$  = work-function.  
 $qX = e^-$  affinity  
 $\Rightarrow$  energy required to extract an  $e^-$  from the CB to vacuum. (energy of  $e^-$  in CB  $\approx E_C$ ).

We consider  $E_{Fn} < E_{fsc}$ .

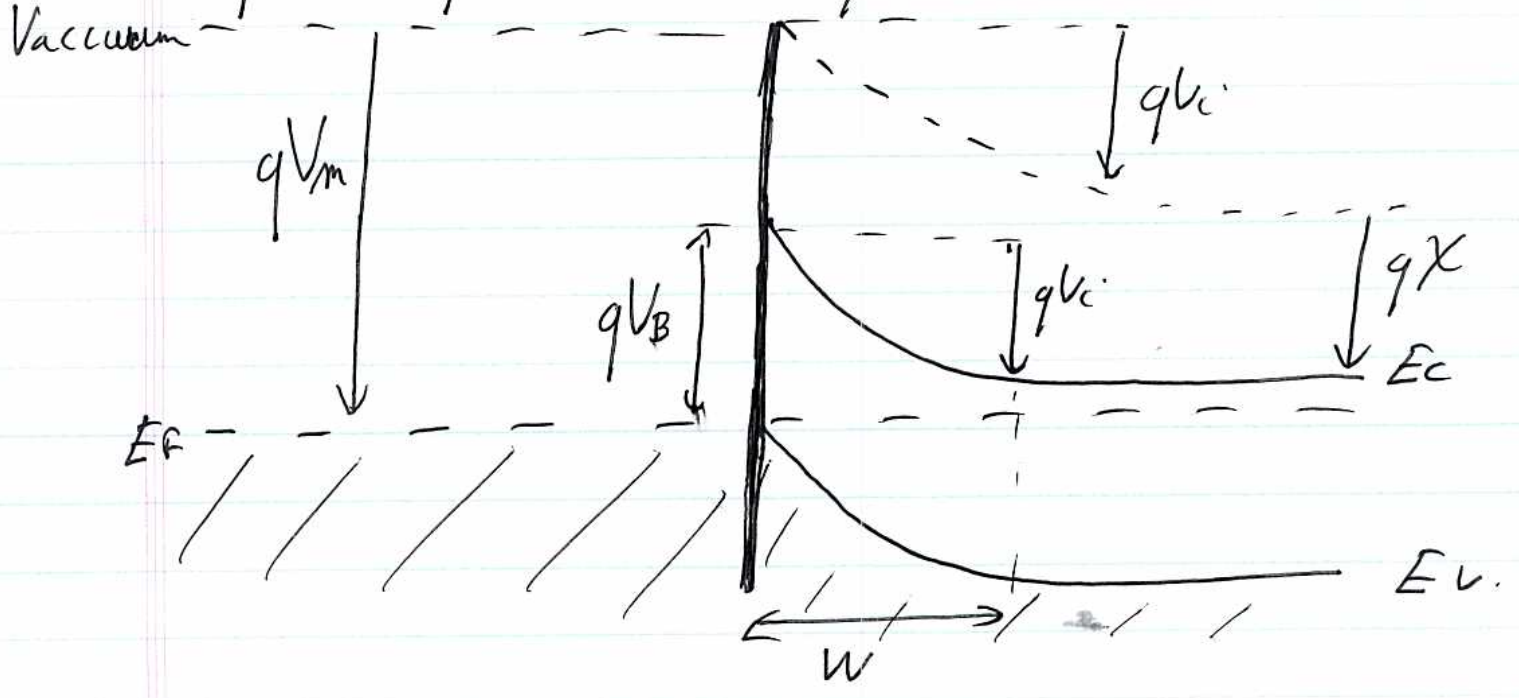
\* Since  $E_c > E_{Fn}$ ,  $e^-$  flow from the semiconductor to the metal until a new equilibrium will be reached.  $e^-$  leave behind positively charged donor atoms and a depletion region is formed in the semiconductor. (with width).

Because of the alignment of the Fermi-levels  $\Rightarrow$

we get a band curvature  $qV_i = q(V_m - V_{sc})$ , which correspond to a potential barrier preventing further  $e^-$  to migrate into the metal.

$E^-$  in the metal see a potential barrier  $V_b$ .

$$qV_b = q(V_m - X) = qV_i + (E_c - E_{Fn})$$



$qV_i, qV_B$  <sup>much</sup> larger than  $\frac{k_B T}{q}$ , only few  $e^-$  can overcome them at room temperature.  
 the bulk current of  $e^-$  migrating from the semiconductor to the metal is  $I_{M \rightarrow S}$  (negative charge).

At thermodynamic equilibrium  $I_{M \rightarrow S} = -I_{S \rightarrow M}$ .

⑥ biased junction

\* if a forward bias  $V_A > 0$  is applied to the junction

$V_i \rightarrow V_i - V_A$   
 more  $e^-$  can flow from the semiconductor to the metal.  
 however  $I_{S \rightarrow M}$  remains constant since  $V_B$  is unchanged

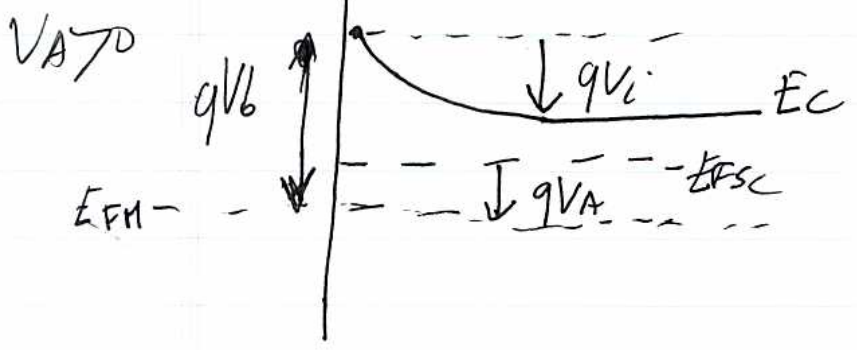
$|I_{M \rightarrow S}| > |I_{S \rightarrow M}|$

\* if reverse bias  $V_A < 0$  is applied to the junction.

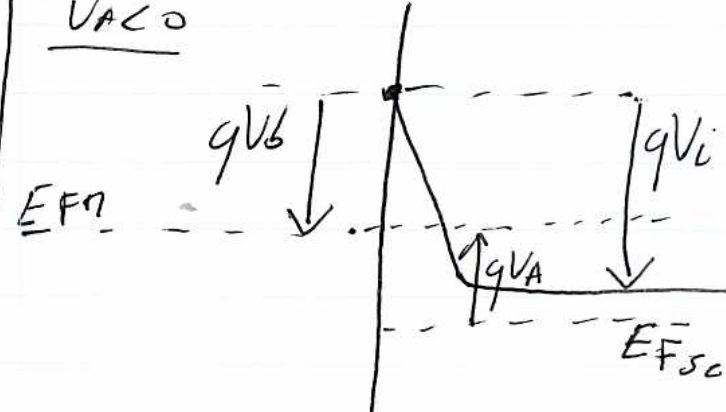
$V_i \rightarrow V_i - V_A$   
 the electron flow from the semiconductor to the metal is reduced. •  $I_{S \rightarrow M}$  remains unchanged

$|I_{M \rightarrow S}| < |I_{S \rightarrow M}|$

Forward bias



Reverse bias





The width of the depletion zone can be calculated using the Poisson equation + depletion approximation.

$$-\frac{d^2 \phi(x)}{dx^2} = \frac{\rho}{\epsilon} = + \frac{q N_d}{\epsilon}$$

at  $x=W$   $\phi(W)=0$  and  $\frac{d\phi(W)}{dx} = 0$ .

$$\Rightarrow + \frac{d\phi(x)}{dx} = \frac{q N_d}{\epsilon} (W-x)$$

$$\boxed{V(x) = - \frac{q N_d}{2\epsilon} (W-x)^2}$$

at  $x=0$   $V(0) = V_i - V_A$ .

$$\Rightarrow -(V_i - V_A) = - \frac{q N_d}{2\epsilon} W^2$$

$$\Rightarrow \boxed{W = \sqrt{\frac{2\epsilon}{q N_d} (V_i - V_A)}}$$

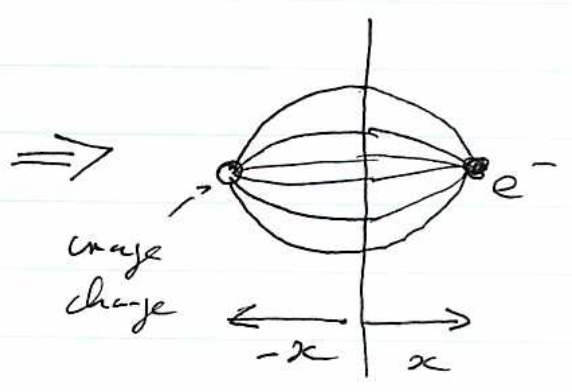
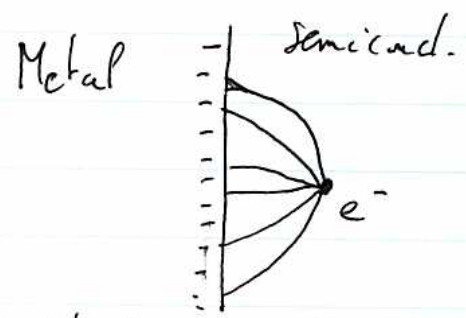
$$\Rightarrow \boxed{E(x) = \frac{-q N_d}{\epsilon} W = - \sqrt{\frac{2q N_d}{\epsilon} (V_i - V_A)}}$$

$$\boxed{E(x) = - \frac{q N_d}{\epsilon} (W-x)}$$

# ③ Schottky effect

A lowering of  $V_b$  is observed due to a mirror charge produced in the metal by  $e^-$  in the semiconductor.

From Electrostatics, we know that when a charge is near a "perfect conductor", a mirror charge of same magnitude but opposite sign is created inside the conductor.



Field lines and surface charges due to an  $e^-$  in close proximity to a perfect conductor

electrostatics force between 2 particles  $\Rightarrow$

$$F(x) = \frac{-q^2}{4\pi\epsilon(2x)^2}$$

$$U = -\int \frac{F}{q} dx = -\int \frac{-q^2}{4\pi\epsilon(2x)^2} dx = -\frac{q^2}{16\pi\epsilon x}$$

$$F = -\nabla U \Rightarrow F = \frac{q^2}{16\pi\epsilon x^2}$$

$$\left. \begin{aligned} F &= qE \\ E &= -\nabla V \\ U &= -qV \end{aligned} \right\}$$

~~For an  $e^-$  in the conduction band the potential energy is  $-\frac{q^2 N d / W - x^2}{2\epsilon} + E_c$~~